



PATENT APPLICATION *IFW \$*

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q77490

Fumiyuki NISHIYAMA, et al.

Appln. No.: 10/669,603

Group Art Unit: 1713

Confirmation No.: 1317

Examiner: Satya B. Sastri

Filed: September 25, 2003

For: POSITIVE RESIST COMPOSITION AND PATTERN FORMATION METHOD USING  
THE SAME

PETITION FOR EXTENSION OF TIME UNDER 37 C.F.R. § 1.136

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. § 1.136, Applicant hereby petitions for an extension of time of one month(s), extending the time for responding to the Office Action of June 13, 2005 to October 13, 2005.

A check for the statutory fee of \$120.00 is attached. The USPTO is directed and authorized to charge all required fees, except for the Issue Fee and the Publication Fee, to Deposit Account No. 19-4880. Please also credit any overpayments to said Deposit Account. A duplicate copy of this sheet is enclosed.

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WASHINGTON OFFICE

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CUSTOMER NUMBER

Respectfully submitted,

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Date: October 13, 2005